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ISSUE DATE

U.S. UTILITY Patent Application

APPL NUM	FILING DATE	CLASS	SUBCLASS	GAU	EXAMINER
10030656	01/11/2002	216		1165 146	Olson 1763

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**CONTINUING DATA VERIFIED:

THIS APPLICATION IS A 371 OF PCT/JP00/05624 08/23/2000

** FOREIGN APPLICATIONS VERIFIED:

JAPAN 11/2411427 08/27/1999

PG-PUB	DO NOT PUBLISH <input type="checkbox"/>	RESCIND <input type="checkbox"/>	
Foreign priority claimed 35 USC 119 conditions met		<input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input checked="" type="checkbox"/> yes <input type="checkbox"/> no	ATTORNEY DOCKET NO 07553.0029
Verified and Acknowledged Examiner's initials			
TITLE : Method of etching and method of plasma treatment			
U.S. DEPT. OF COMM., PAT. & TM-PTO-436 (Rev. 12-94)			

NOTICE OF ALLOWANCE MAILED		CLAIMS ALLOWED	
		Assistant Examiner	Total Claims Print Claim for O.G.
ISSUE FEE			DRAWING Sheets Drwg. Figs. Drwg. Print Fig.
Amount Due	Date Paid	Primary Examiner	
TERMINAL		PREPARED FOR ISSUE	
DISCLAIMER		Application Examiner	
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